

1746 SAH # 2

TRANSMITTAL OF FORMAL DRAWINGS

Docket No.  
FIS920000409EUSI

In Re Application Of: MICHAEL R. SIEVERS, ET AL.

4-8-02

Serial No.

09/887,791

Filing Date

June 22, 2001

Batch No.

Examiner

Ahmed

Art Unit

17461765

Invention: FOCUSED ION BEAM PROCESS FOR REMOVAL OF COPPER



Address to:  
Assistant Commissioner for Patents  
Washington, D.C. 20231

RECEIVED  
SEP 21 2001  
TC 1700

Transmitted herewith are:

two (2) sheets of formal drawing(s) for this application.

Each sheet of drawing indicates the identifying indicia suggested in 37 CFR Section 1.84(c) on the reverse side of the drawing.

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Signature

Peter R. Hagerty  
Registration No. 42,618  
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Dated: September 18, 2001

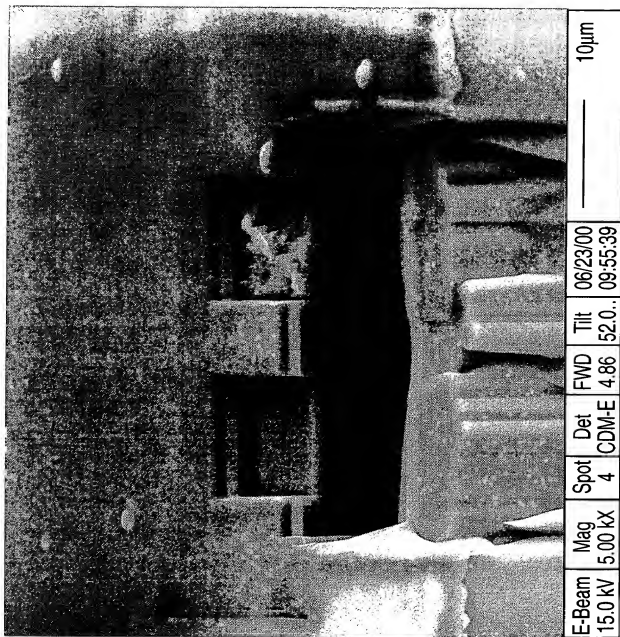
I certify that this document and attached formal drawings are being deposited on September 18, 2001 with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.

Signature of Person Mailing Correspondence

Marjorie R. Humes

Typed or Printed Name of Person Mailing Correspondence





E-Beam	Mag	Spot	Det	FWD	Tilt	06/23/00	10µm
15.0 kV	5.00 kX	4	CDM-E	4.86	52.0.	09:55:39	

FIG. 2